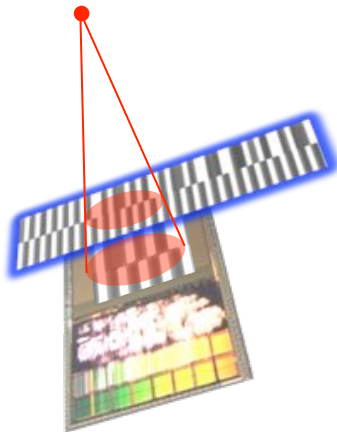


Vision Embedded Systems

CSEM, SpaceCoder Technology, June 2013

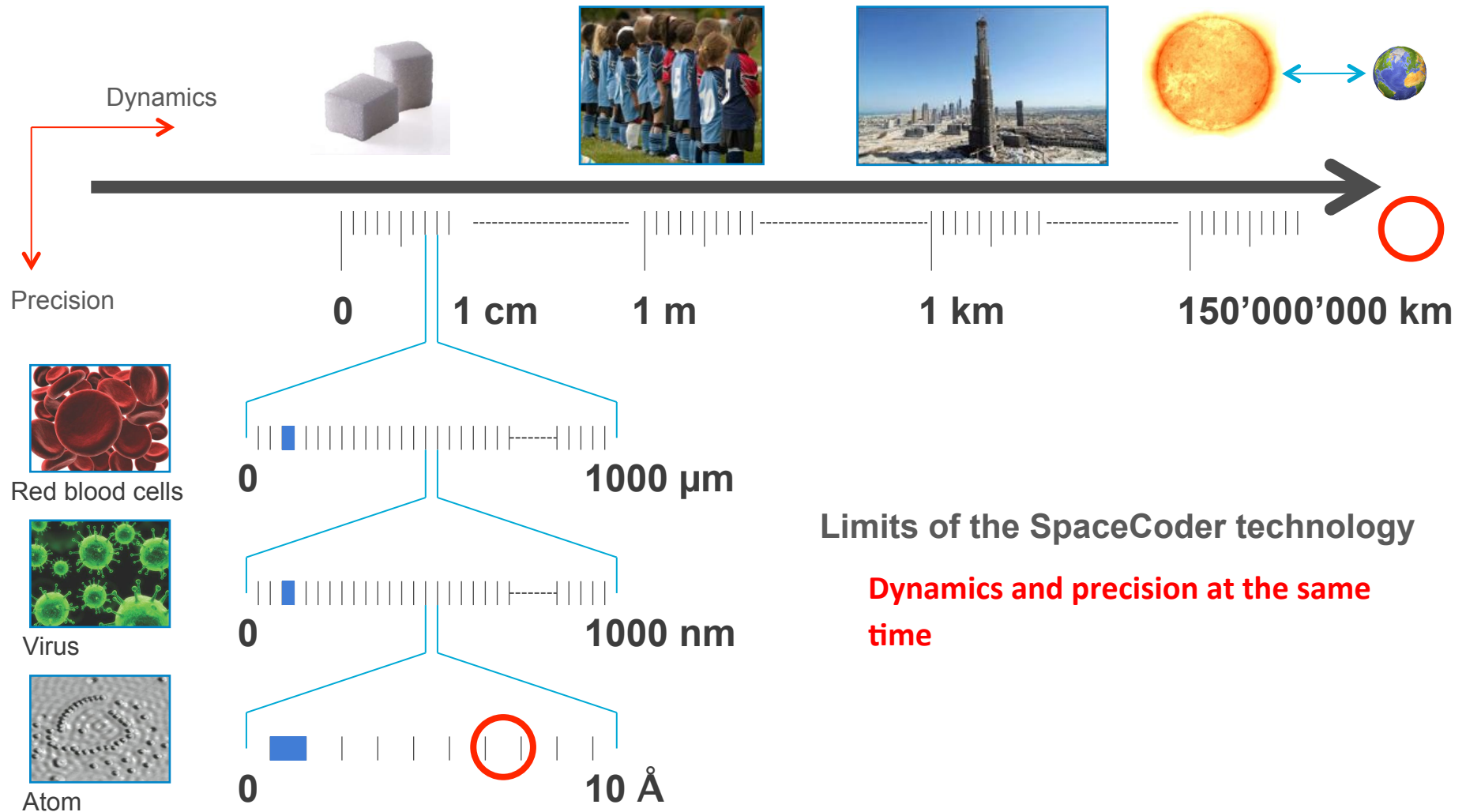




Outline of this presentation

- Birth of a technology: the Electric Power Assist Steering (EPAS) sensor
- Measuring nanometric displacements
- Multidimensional extensions: shadow imaging for 1 DOF to 6 DOF measurements
- Vision & microelectronic technologies: the perfect matching
- Examples: airplane weight balance, optical accelerometers and 6 DOF pointers
- Conclusion

Sizes ... from 1 Å to the infinite

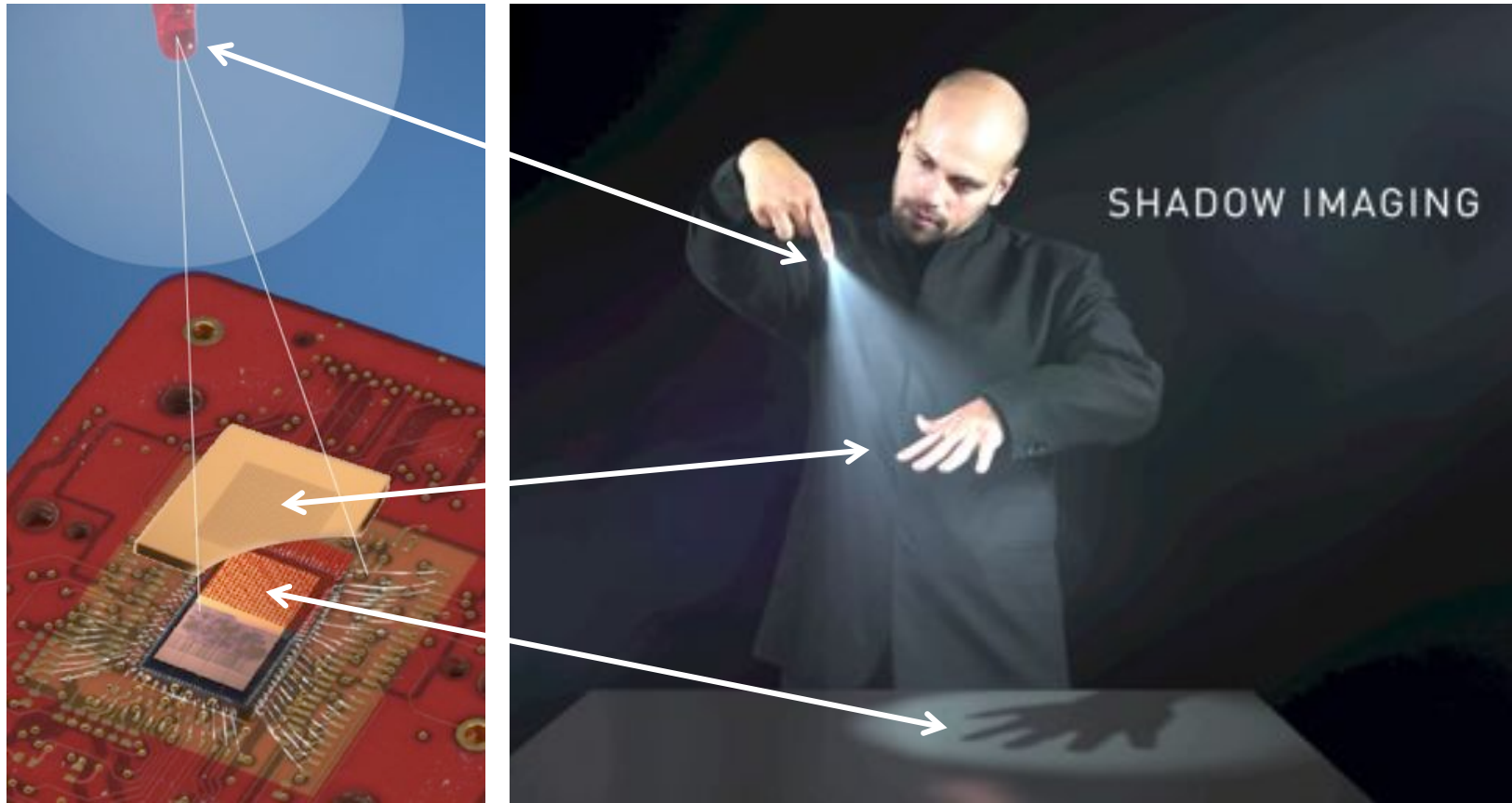


Limits of the SpaceCoder technology

Dynamics and precision at the same time



spaceCoder principle – Shadow Imaging



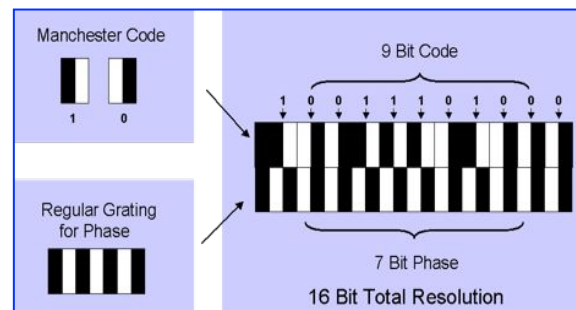
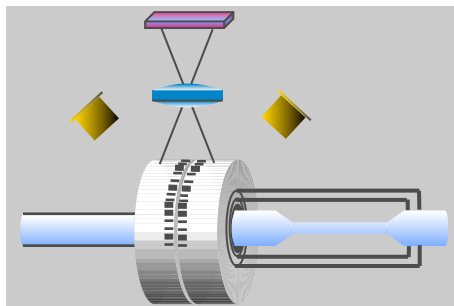


Optical torque sensor for EPAS applications



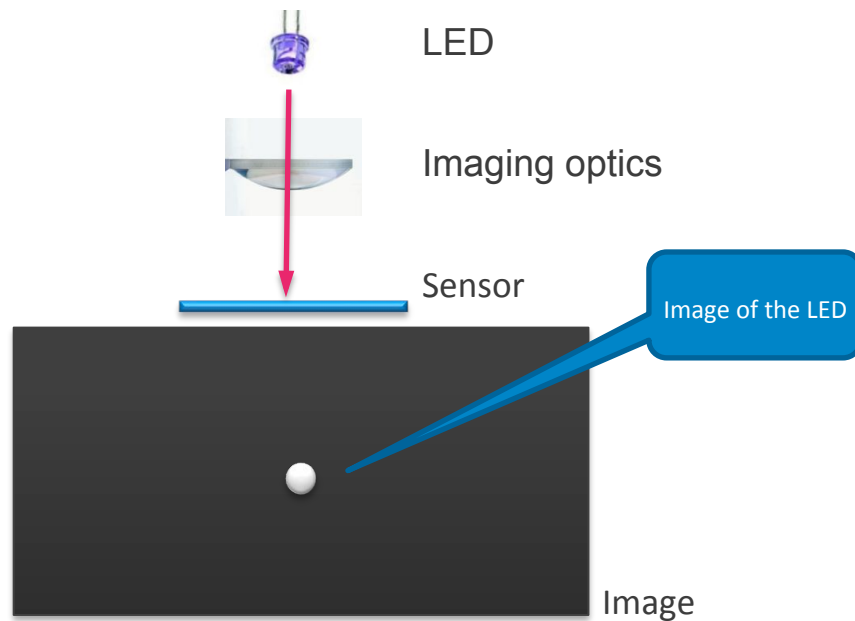
Measure torque, absolute angle and angular rate

- 4 clock cycles for all computing
- Torque precision: 0.05 Nm
- Angle resolution: 18 bits
- Environmental: -40 to 125 °C
- Tangent pre-distorted flash ADC (patented)
- Robust Sensor with phase extraction (patented)
- Power consumption: 5 mA



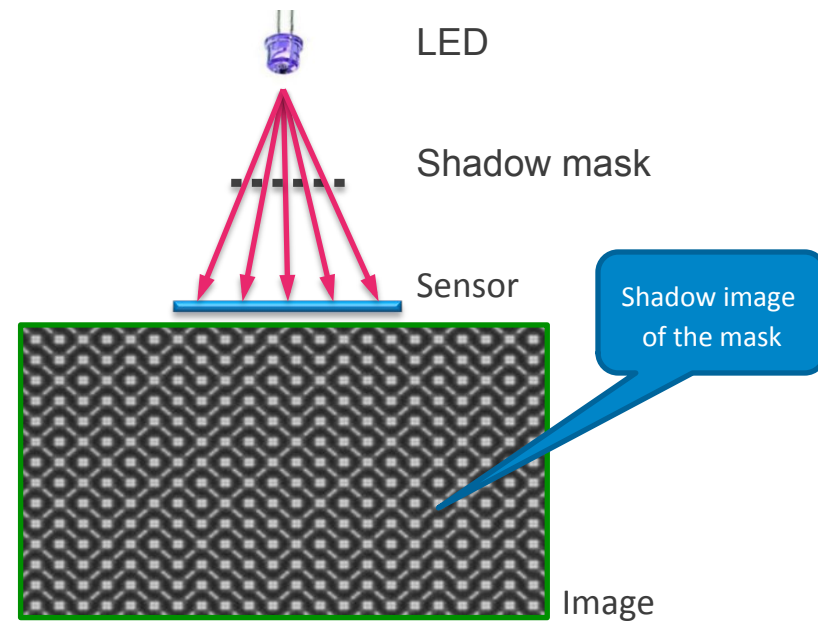


Calculating X-Y position of the LED



Center of gravity of the light spot. The information is **LOCAL**, carried only by **few pixels**

Limited precision accuracy in the order of the pixel size ($5\text{ }\mu\text{m}$)



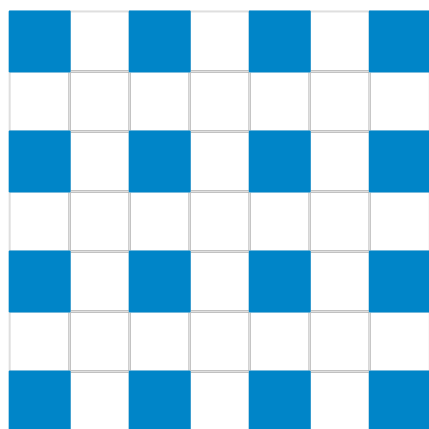
High precision phase measurement of periodic signal. The information is **distributed** into entire image **ALL pixels carries LED position info**

Very HIGH precision & accuracy 1'000 times sub-pixel ($0.005\text{ }\mu\text{m}$) is reached

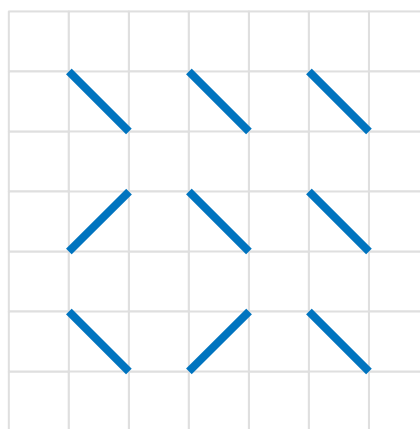


Pattern for 2D absolute position measurement

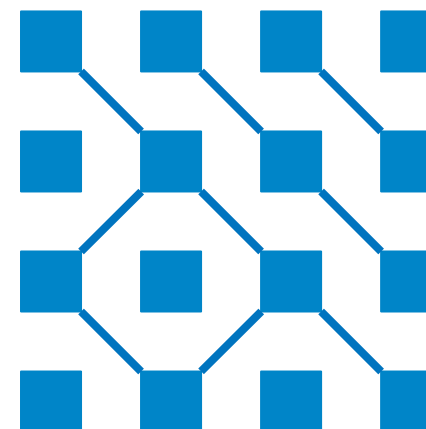
regular grating
for **high-precision, relative**
measurement



binary code
for **low-precision, absolute** measurement

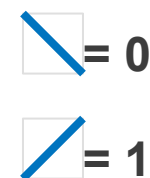


combined code
for **high-precision, absolute** measurement



Pascal Heim, Edo Franz, Péter Masa
Système de positionnement 2D à mesure de phase en quadrature
CSEM RAPPORT D'INVENTION No. 06/37

0 0 0
1 0 0
0 1 0

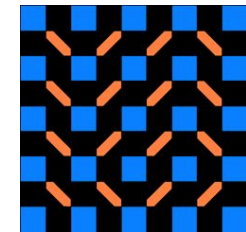




Absolute nanometric measurement system

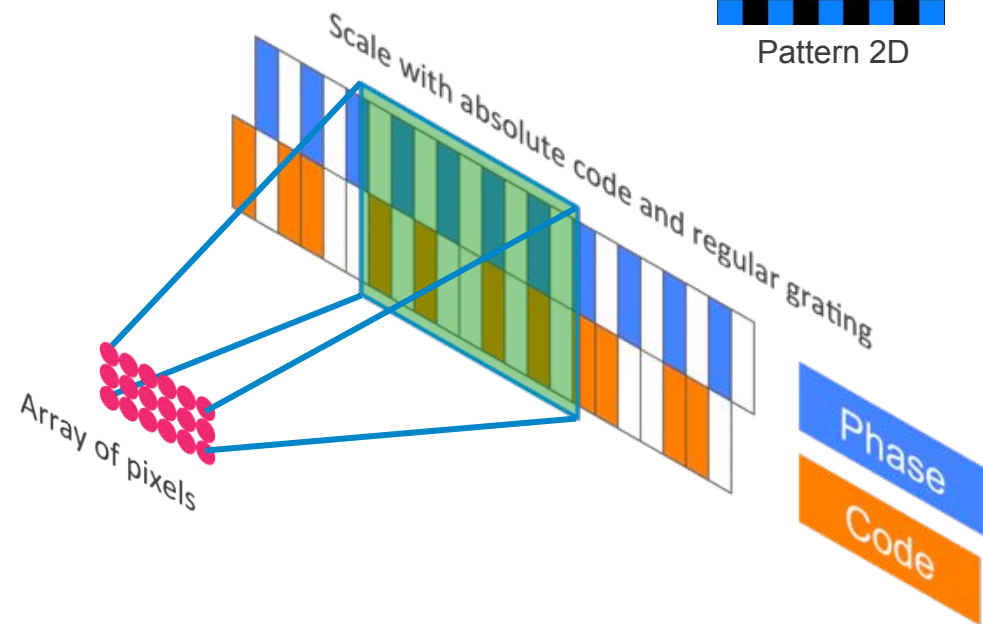
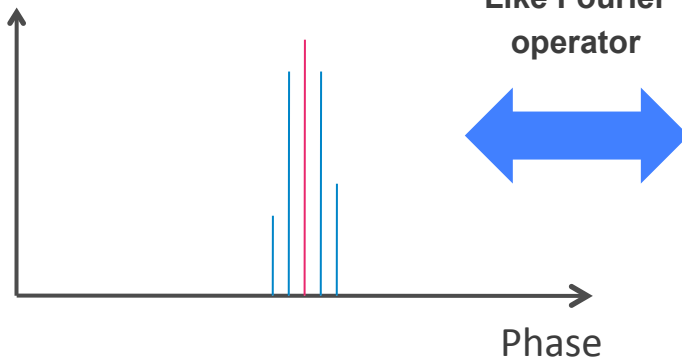
How to measure large absolute distances with nanometric resolution?

- 2 types of markings; an **absolute code** and a **regular grating**
- The **absolute code** provides the MSB of the measurement
- The phase of the **regular grating** gives the LSB
- Each pixel acts as a single sensor
- We take advantage from the statistics



Pattern 2D

Probability density of
Phase measurements

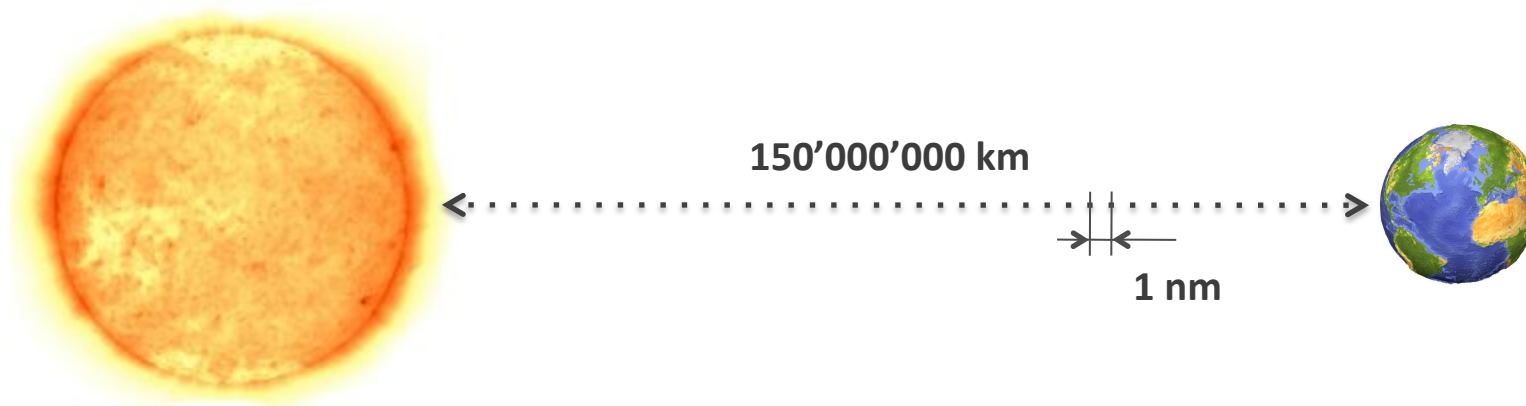
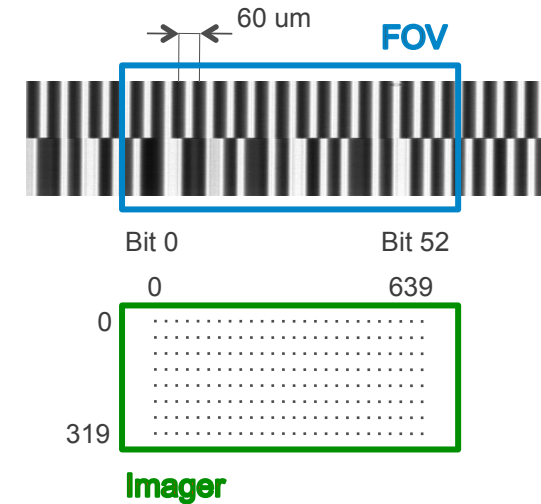




Absolute nanometric measurement system

The limits of the measurement principle: an example:

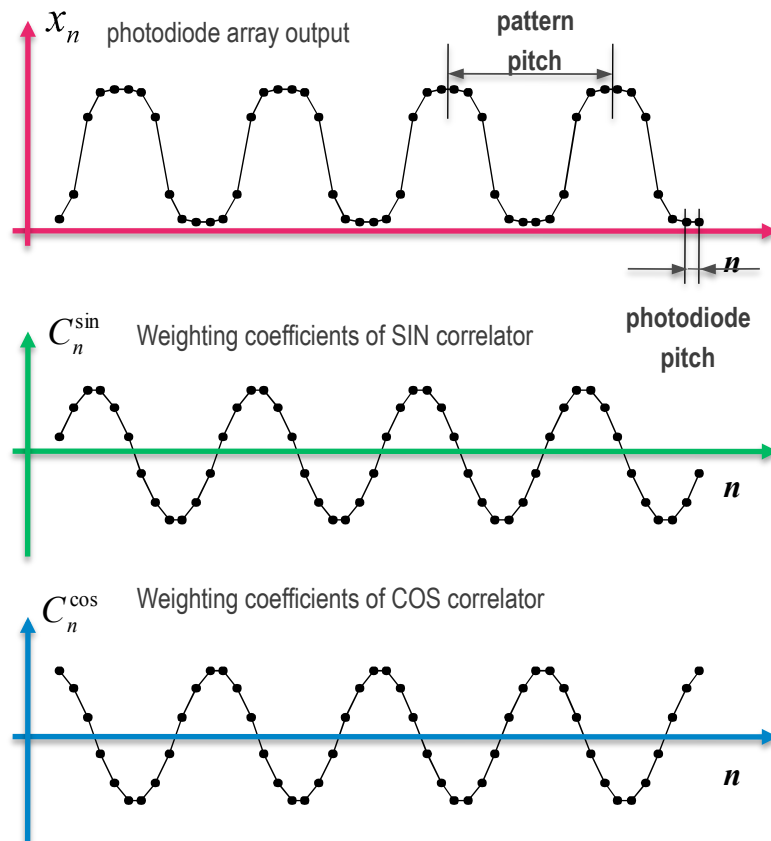
- Low cost, **60 μm period**, chromium-plated scale
- Low cost, low resolution VGA imager (**640 x 320 pixels**) having **5 μm pixels** fixes $60 / 5 =$ **12 pixels / period**
- This allows to represent an absolute code of $640 / 12 =$ **53 bits**; and to interpolate with a factor 60'000 (**16 bits**) for resolving **1 nm**
- 53 + 16 bits represent **1 nm precision** over $\sim$ **590'000'000 km**!





Fine position measurement, vector decomposition

Field Of View



Given $X = X_n$, a periodic pattern, an n -element vector of photodiode outputs α is the phase or position of X

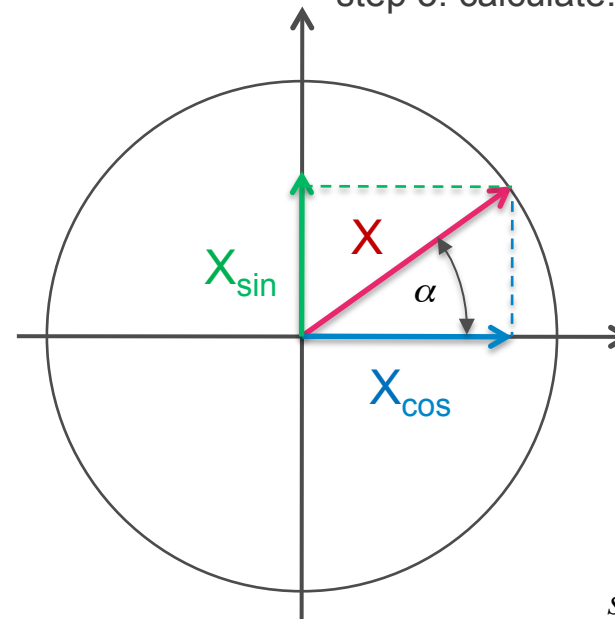
3 Steps to calculate α : step 1: calculate:

$$X_{\sin} = \sum_n X_n C_n^{\sin}$$

step 2: calculate:

$$X_{\cos} = \sum_n X_n C_n^{\cos}$$

step 3: calculate: $\alpha = \arctan\left(\frac{X_{\sin}}{X_{\cos}}\right)$

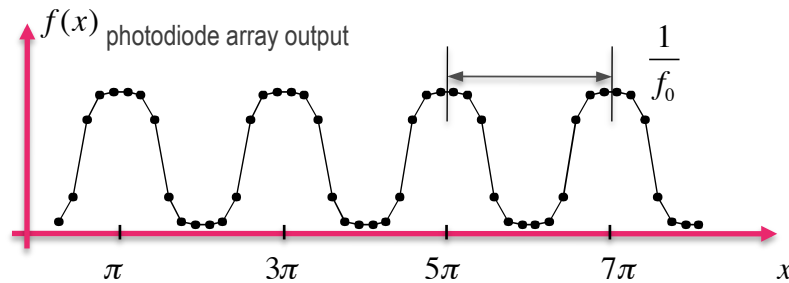
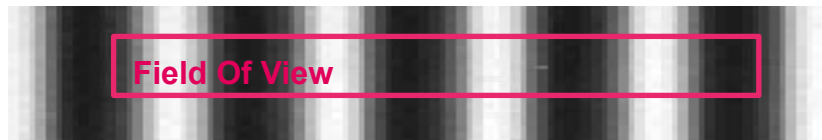


vectors: $X, X_n, C_n^{\sin}, C_n^{\cos}$

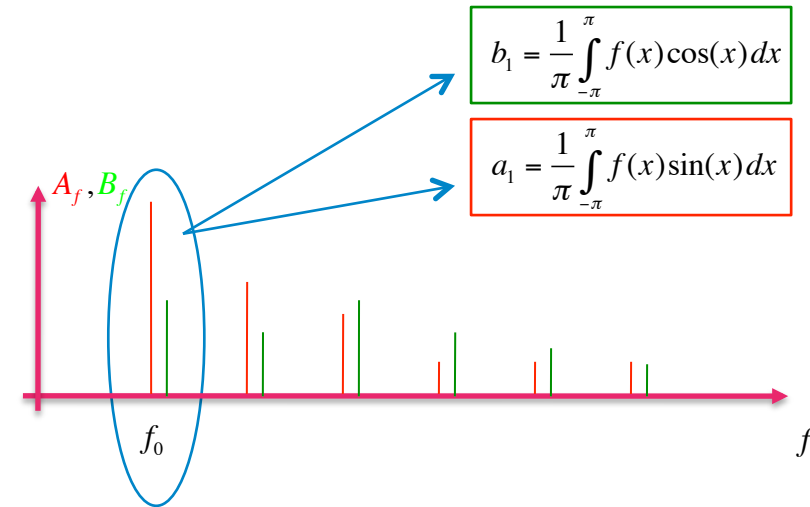
scalars: $X_{\sin}, X_{\cos}, \alpha$



Insensitive to marking quality



$$f(x) = a_0 + \sum_{n=1}^{\infty} [a_n \cos(nx) + b_n \sin(nx)]$$

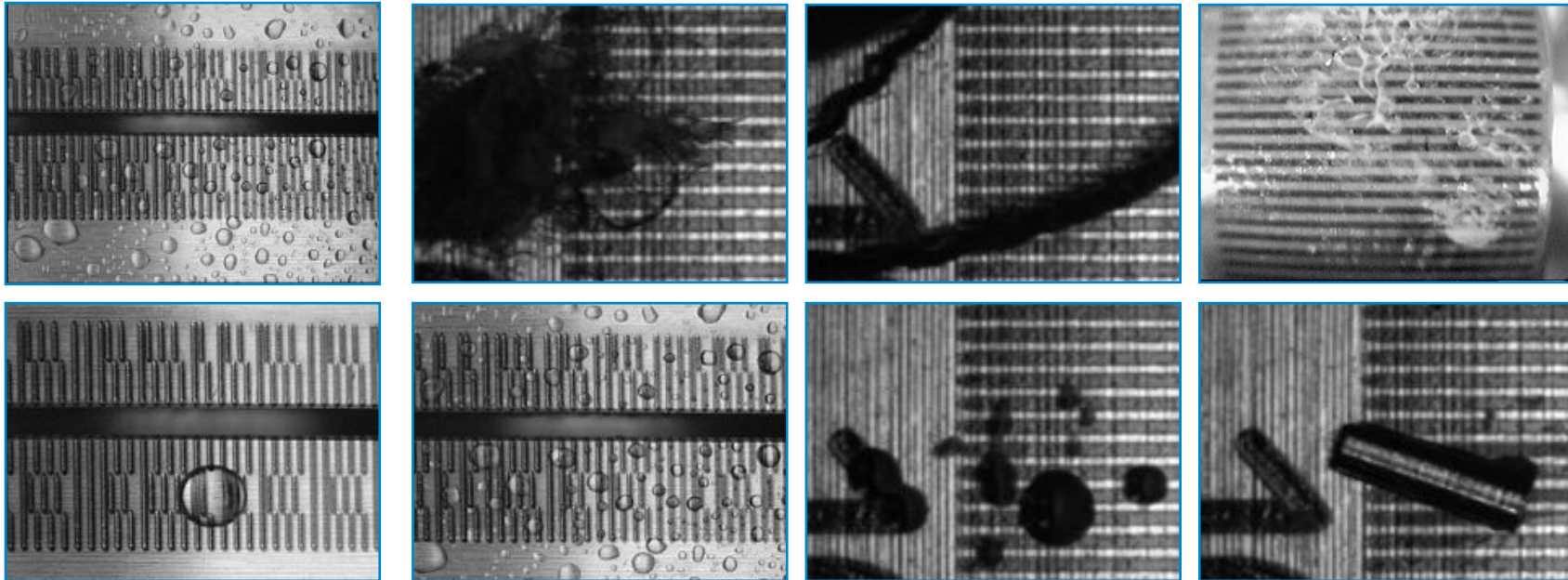


Where is the information ?

- The information **is the phase of the fundamental** frequency ...
- ... which **is distributed in the entire** image (all pixels contain information about it!)
- The phase is **largely insensitive** to the printing quality of the marking (a_1 and b_1 **affected only by the spatial regularity** of the marking)
- Large redundancy; the method **tolerates large degradations** of the marking



Robust principle



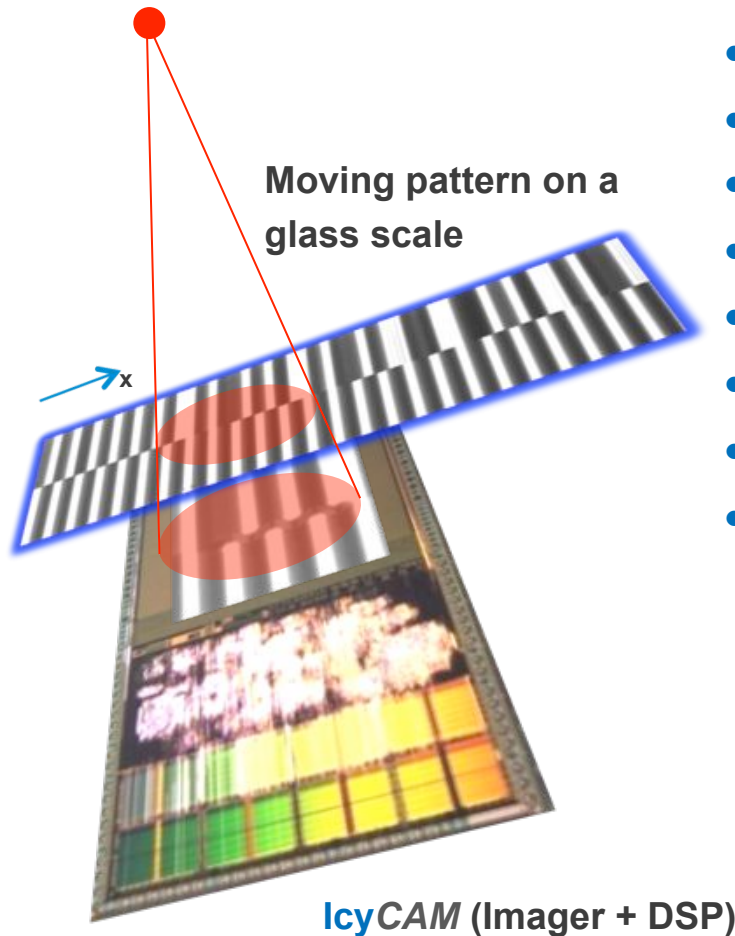
Extensive analysis and verification proves the robustness of the concept for automotive

- Phase information is **distributed in the entire FOV**
part of the pattern **can be corrupted or occluded**



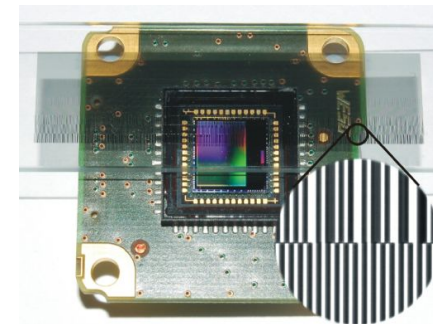
Shadow imaging: absolute 1 DOF measurement

Fixed light source



Main benefits

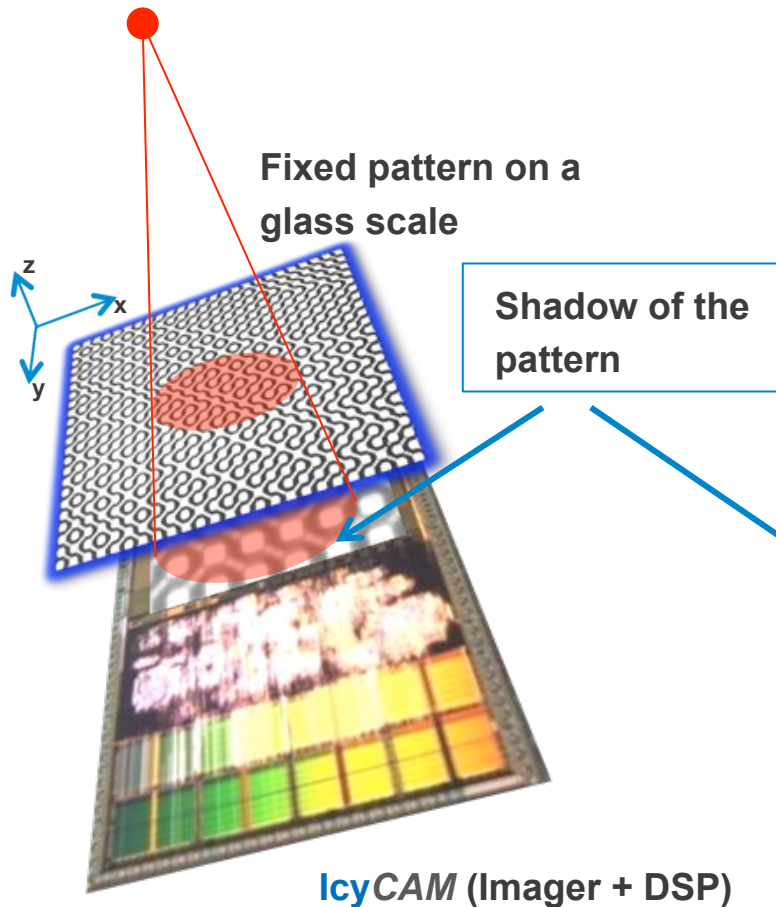
- No lenses
- Contact-less **1 DOF** optical measurement
- True **absolute** position
- Suitable for **linear** or **circular** encoders
- Precision better than **1 nm**
- Practically **infinite** dynamics
- No **drift** nor **calibration**
- Many implementations possible (**camera**, **ASIC**, **DSP**, **FPGA**) from quick solution to peak performance combined with low cost





Shadow imaging: absolute 6 DOF measurement

Moving light source $p = f(x, y, z, \alpha_x, \beta_y, \gamma_z)$



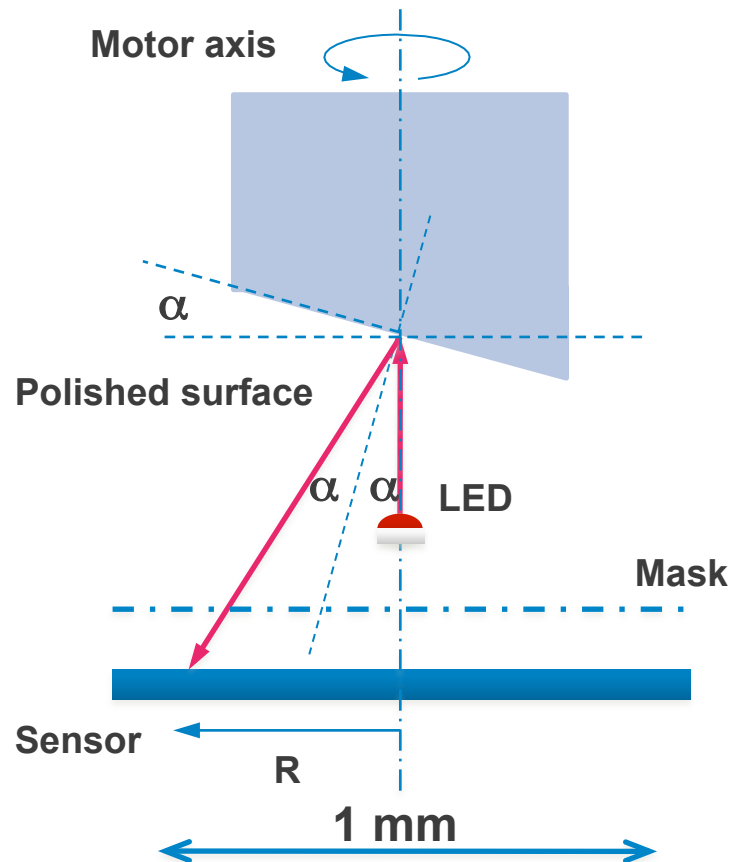
Main benefits

- No lenses
- **Absolute position** of the light source
- Small volume (size of a **sugar cube**)
- **Multi-axes** $x, y, z, \alpha_x, \beta_y, \gamma_z$ 6 degrees of freedom measurements
- Precision close to **10 nm** (x, y) and **100 nm** (z)
- No **drift** nor **calibration**

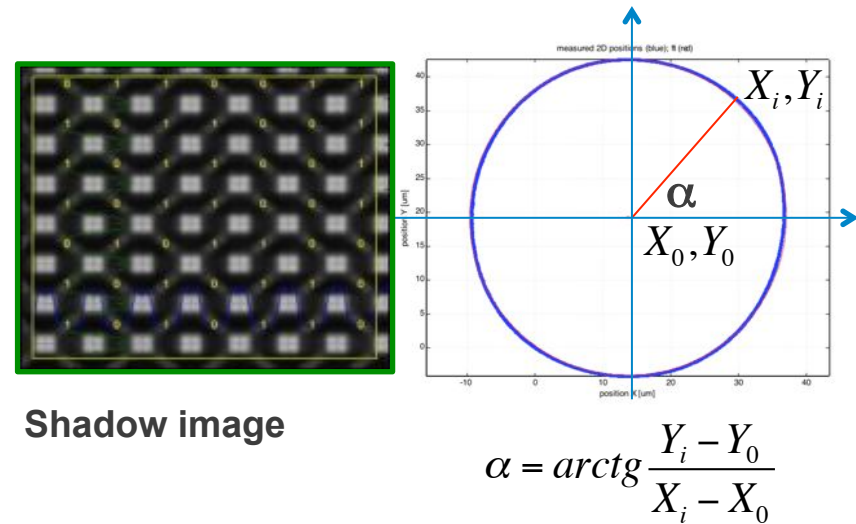




Rotary encoders:

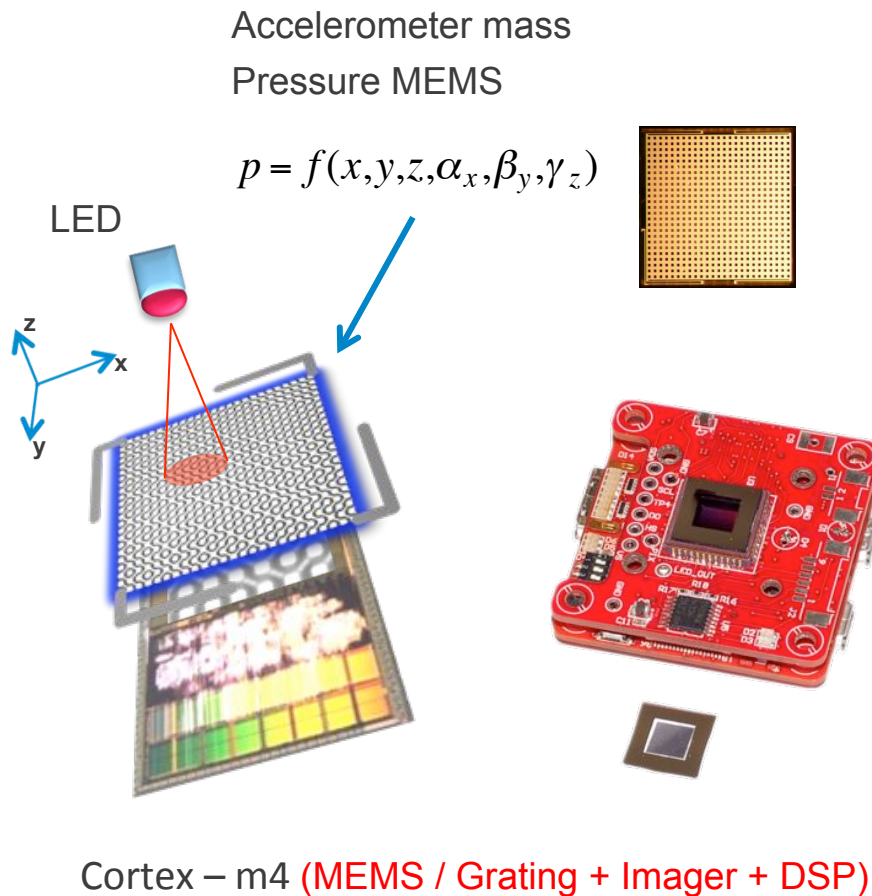


- No need for an encoder disk
- Insensitive to the assembly tolerances
- Small size and volume
- No inertia (for end-of-shaft arrangements)
- No drift
- One shot calibration to determine X_0, Y_0





Absolute 6 DOF MEMS sensor



Main benefits

- No lenses
- Small volume (size of a **sugar cube**)
- **Multi-axes** $x, y, z, \alpha_x, \beta_y, \gamma_z$ **absolute 6 degrees** of freedom measurements
- Precision close to **10 nm** in **all the axes**
- **On chip** signal processing
- **Digital output** of ...
 - Acceleration,
 - Speed,
 - Pressure,
 - Deformation,
 - 6 DOF absolute position,
 - Other processed information,
- ... via **SPI** or other **μC bus**

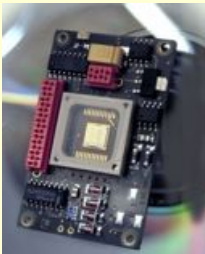


Various platforms proposed

Full-custom ASIC



High-speed
Harsh environment
Low-Power
Fixed configuration

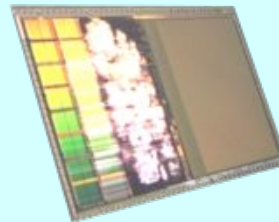


Generic ASIC + DSP

Optical front-end

DSP

High-speed
Harsh environment
Flexible
Scalable
Space compatible



Imager + DSP

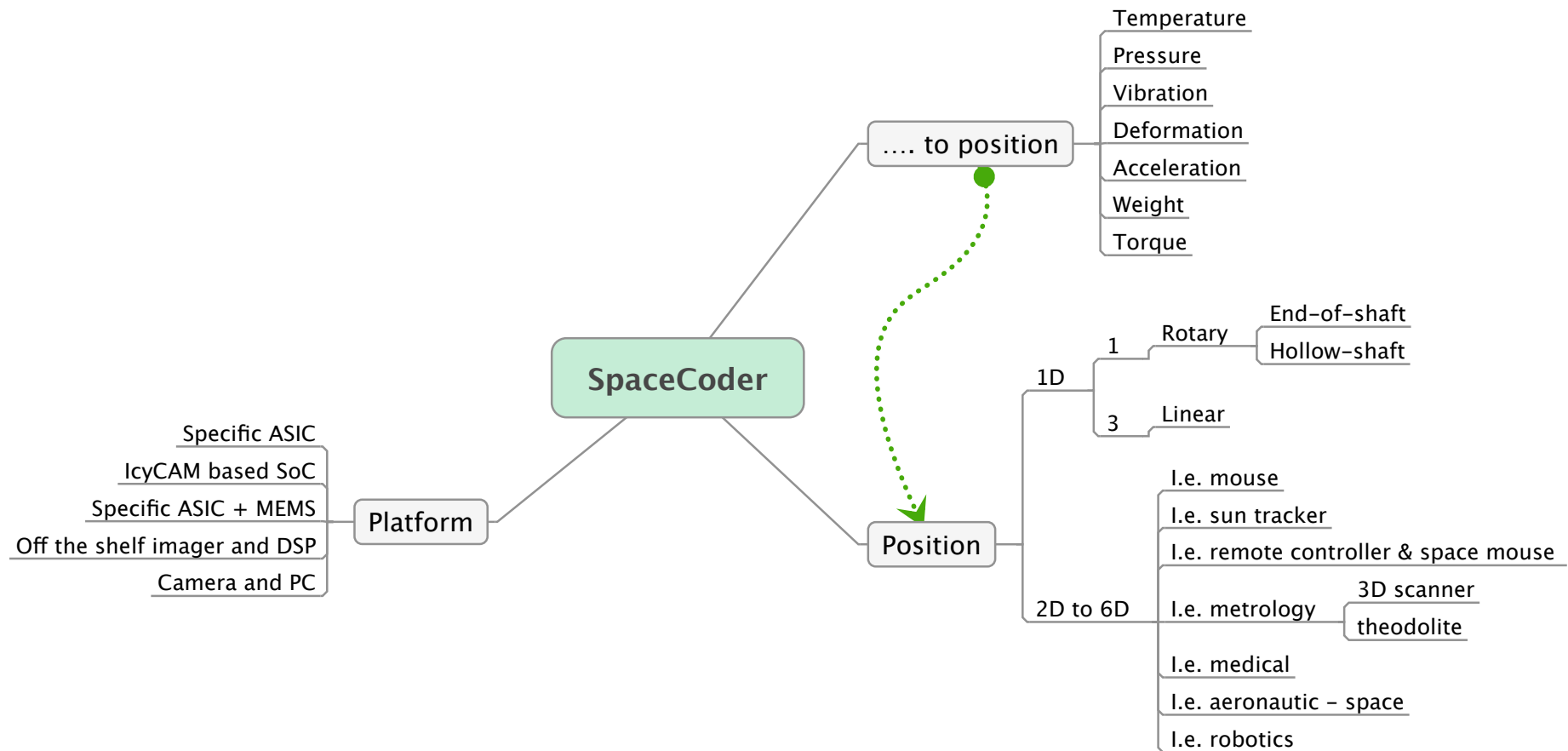
Imager

DSP

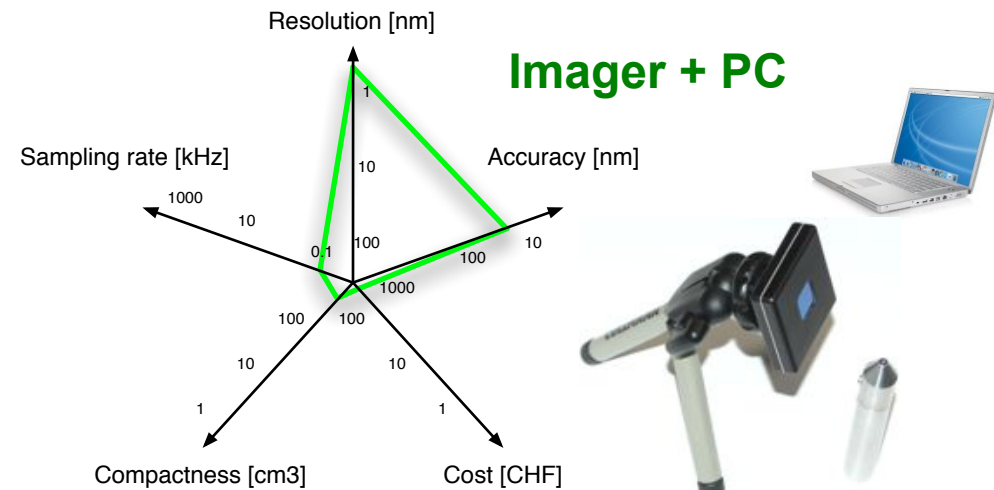
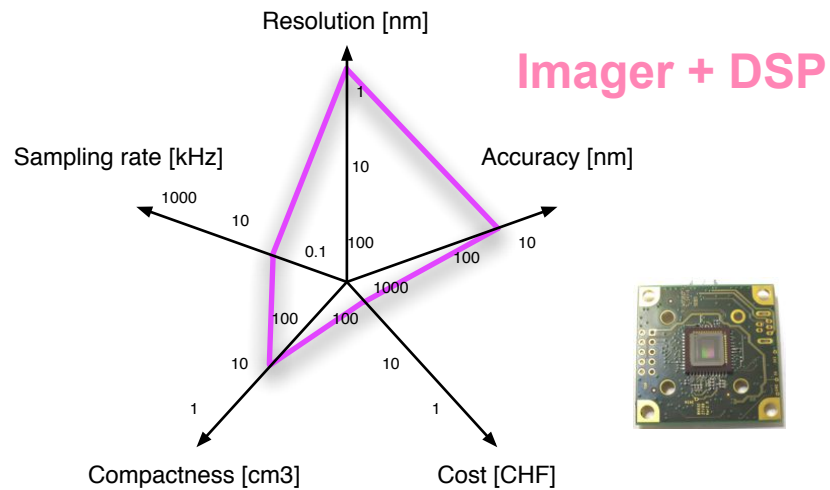
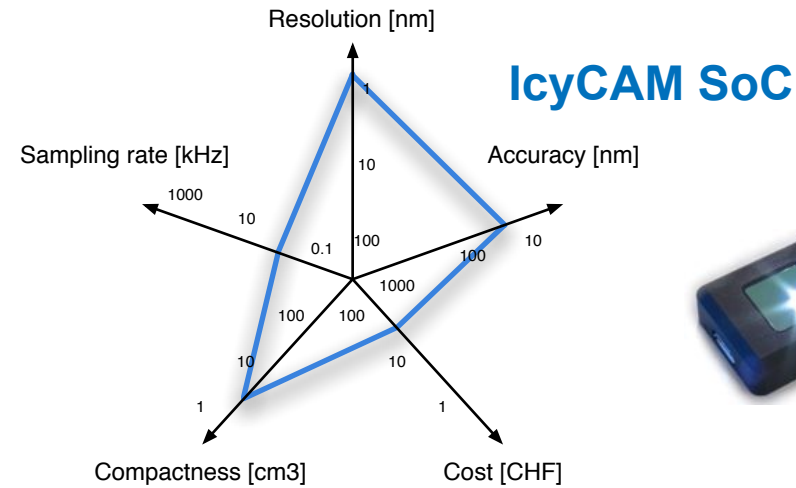
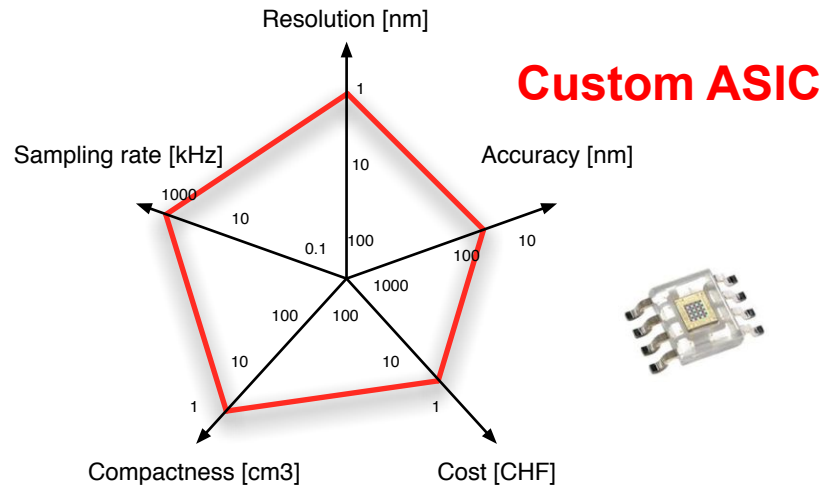
Flexible
Scalable
Space compatible



SpaceCoder as a sensor

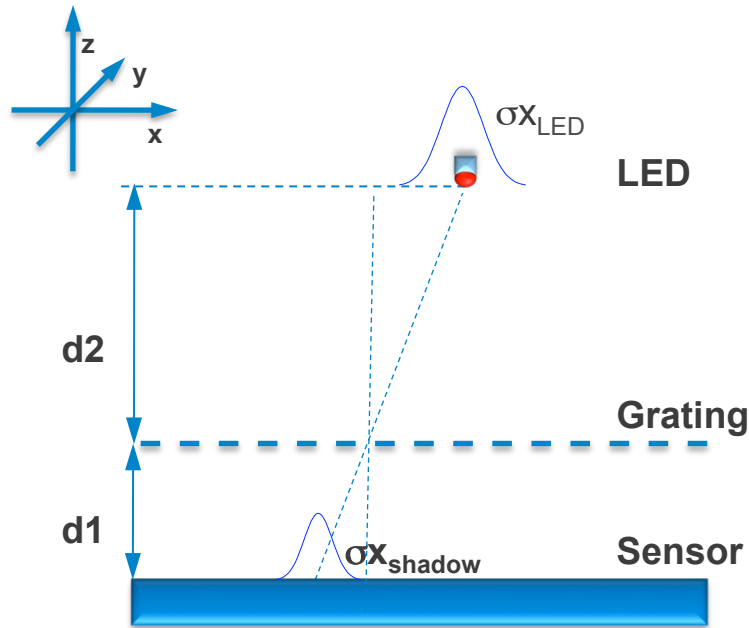


SpaceCoder as a sensor





X,Y precision, accuracy



Noise of the shadow position measurement:

$\sigma_{X_{\text{shadow}}}$

From shadow to LED position:

$$\sigma_{x_{LED}} = \sigma_{x_{\text{shadow}}} \frac{d_2}{d_1} = 0.005 \mu\text{m} \cdot \frac{100 \text{ mm}}{1 \text{ mm}} = 0.5 \mu\text{m}$$

Precision $\sigma_{X_{\text{shadow}}}$ affected by:

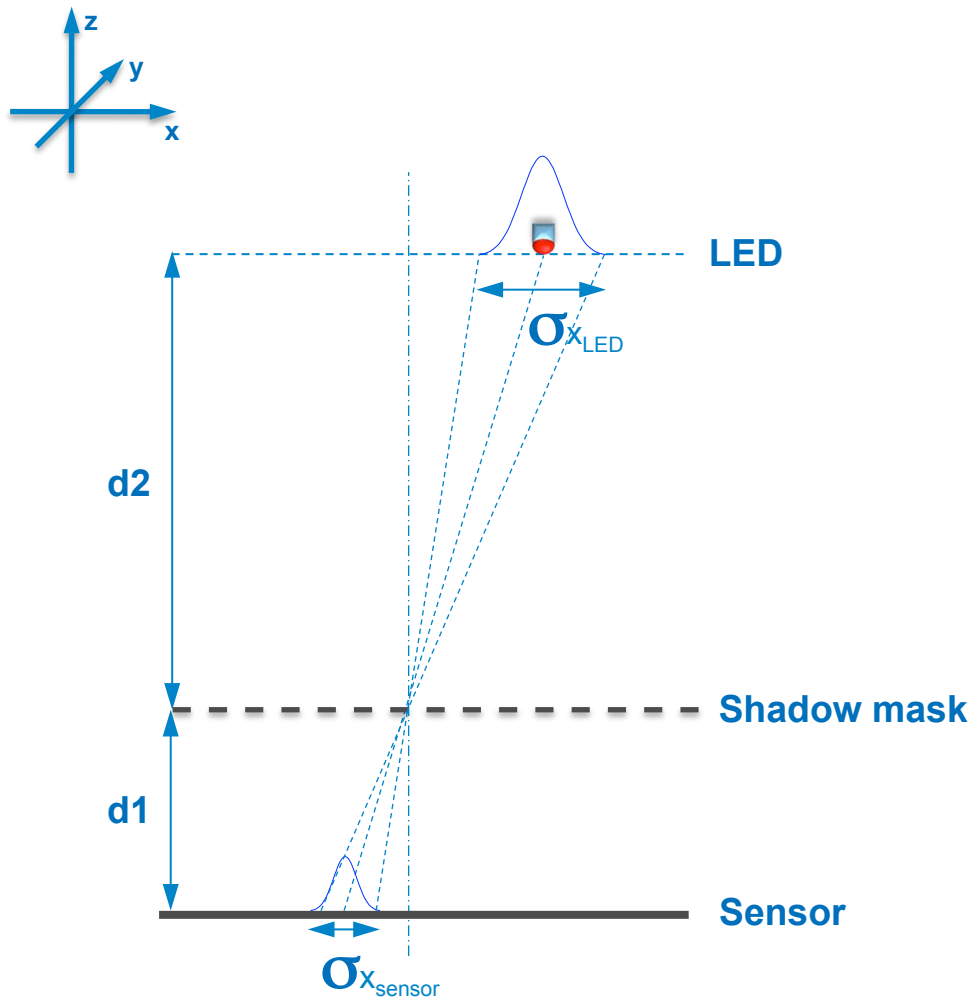
- Mainly by shot noise, image contrast, photon flux: ~0.1 to 5 nm
- Grating pitch (proportional)
- Noise of: ADC, dark current, read-out, kTC, etc: 0.1 to 5 nm
- **Achievable precision: ~0.25 nm**

Accuracy $\sigma_{X_{\text{shadow}}}$ affected by:

- Accuracy of the grating (thermal, mechanical stability, etc)
- Frequency mismatch: ~100 to 5'000 nm
- Contamination: ~ 100 to 5'000 nm
- Grating pitch (proportional)
- Refraction with certain gratings
- Overall mechanical and thermal stability of the system excluding the sensor: ~? nm
- **Achievable Accuracy w/o calibration: ~100 to 1'000 nm**
- **Achievable Accuracy with calibration: ~10 to 1'000 nm**



Sensor-Level precision VS 3D precision (X,Y)



Example: LED (X,Y) precision at 1m

$\sigma_{x_{\text{sensor}}} \# 5 \text{ nm}$

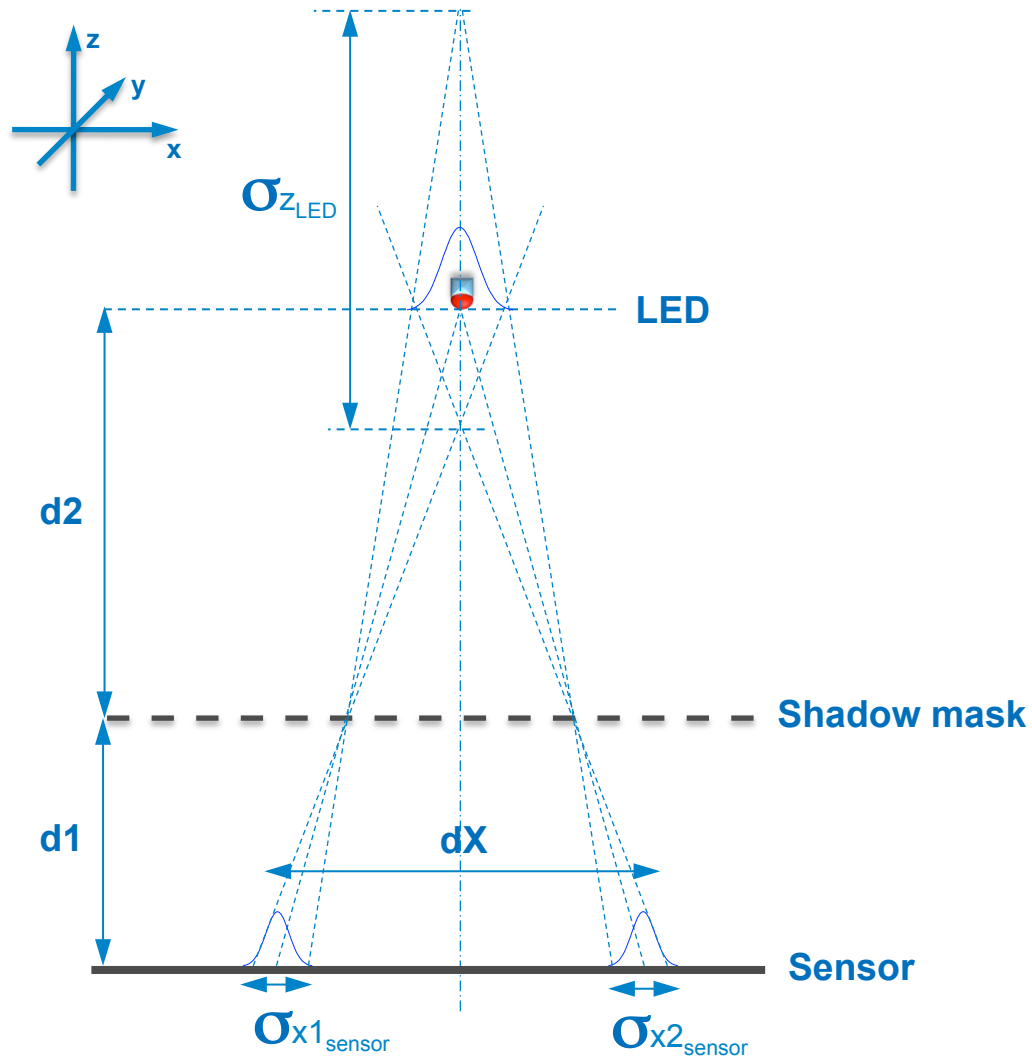
$d2 \# 1 \text{ m}$

$d1 \# 2 \text{ mm}$

$$\sigma_{x_{\text{LED}}} = \frac{d2}{d1} \sigma_{x_{\text{sensor}}} = 2.5 \mu\text{m}$$



Sensor-Level precision VS 3D precision (Z)



Example: LED (Z) precision at 20 cm

$\sigma_{x_{\text{sensor}}}$ # 5 nm

d1 # 2 mm

Aptina sensor

dX # 1.4 mm $\Rightarrow \sigma_{z_{\text{LED}}}$ # 140 μm

E2V sensor

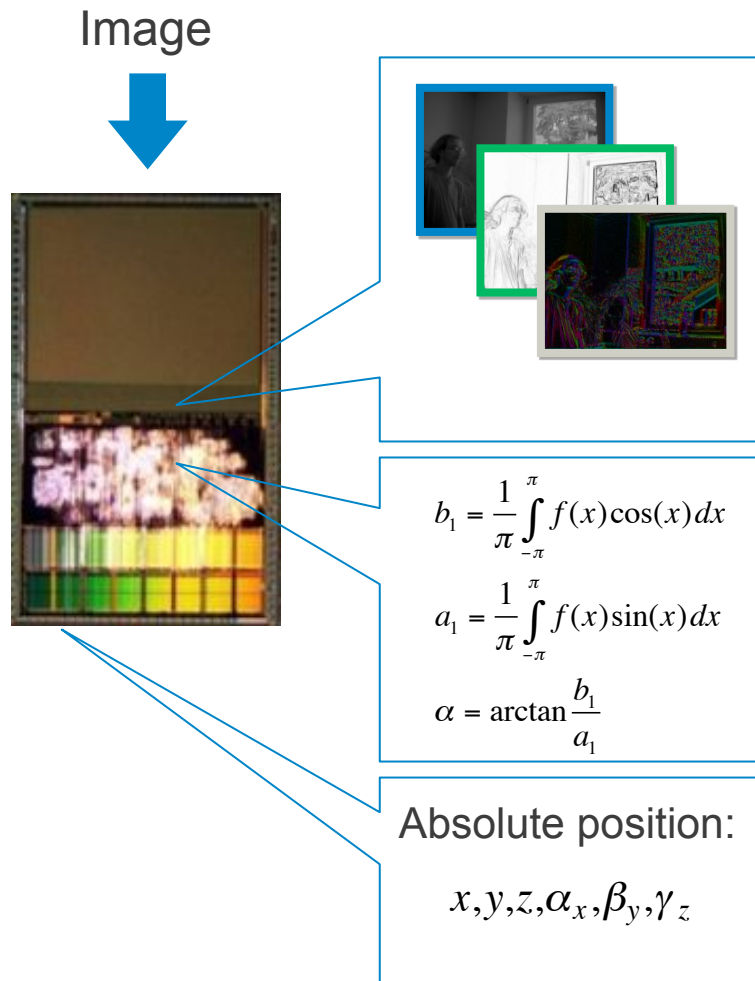
dX # 2.6 mm $\Rightarrow \sigma_{z_{\text{LED}}}$ # 70 μm

2 sensors

dX # 10 cm $\Rightarrow \sigma_{z_{\text{LED}}}$ # 4 μm



IcyCAM : a single chip measuring system

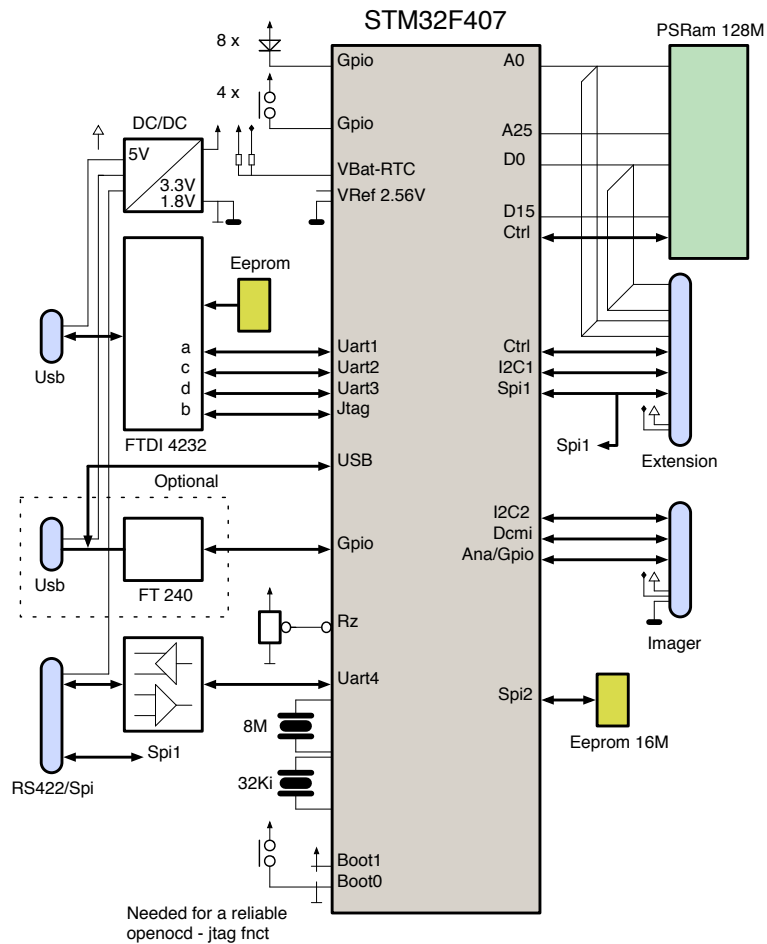


- Technology: 0.18 μm
- Front-end: 320 x 240 pixels (QVGA)
- Luminance: digital log representation
- Contrast: magnitude and orientation ($M e^{j\theta}$)
- Dynamic range: 130 dB
- DSP: 50 MHz DSP icyflex
- Memory: 128 Kbyte on chip SRAM
- I/Os: UART, SPI, PPI, SDRAM, ..
- Programmable: GNU tool suite (gcc, gdb, gas)
- Suitable for medium speed (~ 1 kHz) high precision
1 DOF, 2 DOF or 6 DOF measurement systems

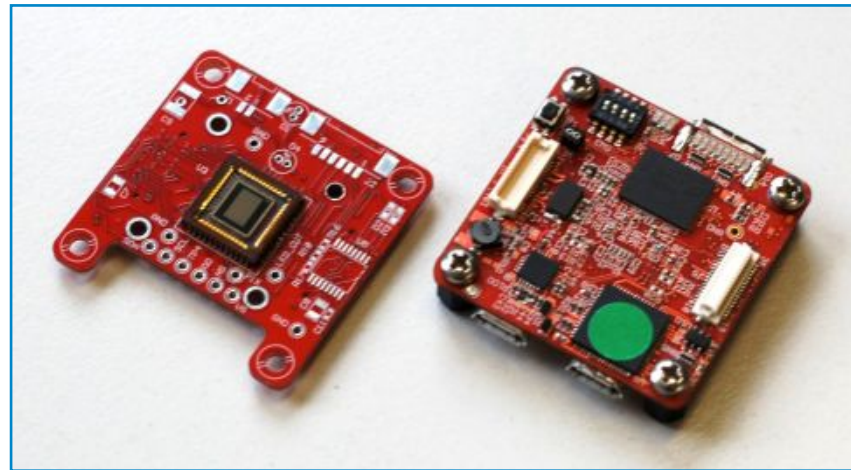




ARM® Cortex™-M4 vision & metrology platform



- ARM® Cortex™-M4 DSP instructions
- 200 MIPS @ 160MHz, 40μW/MHz
- Example: absolute encoder:
 - 1D or 2D linear : resolution X,Y: **5 nm**
 - Rotary: resolution: **0.5 urad, 0.1 arcsec**
 - 3D mouse or remote controller
 - Sampling rate: **300 Hz (up to 3 KHz)**
- Industrial interfaces(SPI, PPI, UART, GPIO, etc.)
- Dimensions (35 x 35 mm)

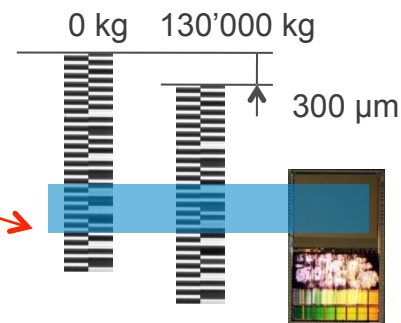




Application: A380 weight balance



- Balance of the airplane weight for reducing the fuel **consumption**
- Measurement of airplane weight with **1 kg** of precision
- The max. weight is **~ 520'000 kg** distributed on 4 points
- We have to measure **1 kg to 130'000 kg** **resolution (18 bits)**

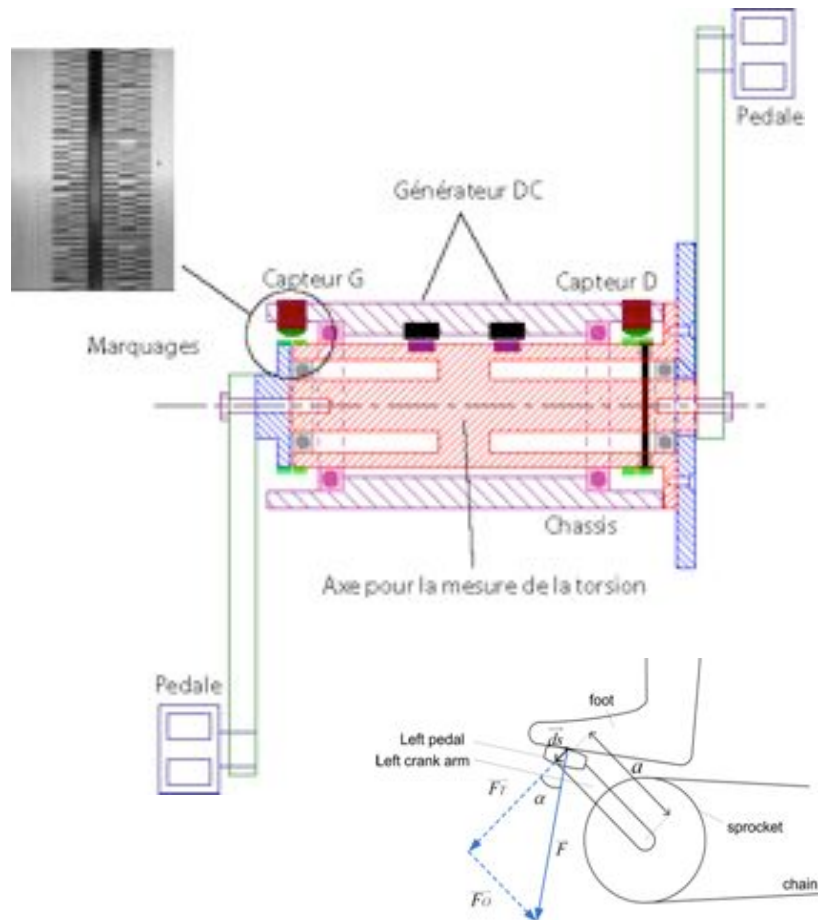


The load causes a deformation and a displacement of a marking

$$1kg \rightarrow \frac{300 \times 10^{-6}}{130 \times 10^3} = 2.3nm$$



Cycling performance monitoring and analyzer



Characteristics

- **Accurately measures** torque on both pedals as a function of exact pedal position and pedal speed. Monitors cycling technique and performance with the utmost precision.
- **Low cost** sensor designed for direct integration in the standard parts such as the bottom bracket.
- **Battery-less** operation, can be directly powered during the pedal movement.
- **Simple system:** encoder ASIC, LED, a marked cylinder, torsion bar. The last 2 are integral part of the bottom bracket.
- Different configurations are possible: i.e. the system could also be **integrated in the pedals or in the crankset**.



Bottom bracket



Crankset



pedal

μMouvement analysis

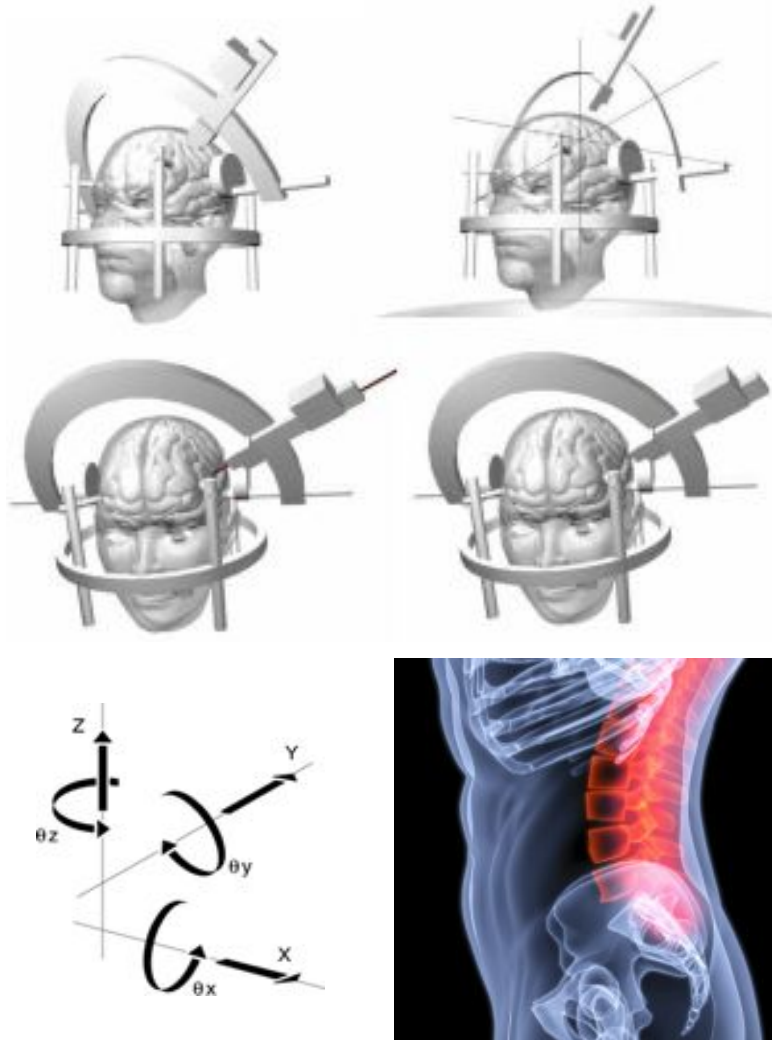


Main benefits

- **No inertia**, passive observation
- **Multi-axes** analysis
- **Precise** characterization of mobile elements



Precise positioning of surgical tools



Characteristics

- Micrometer precision 3D-6D positioning of surgical tools
- For computer-assisted, robotic surgery, precise, controlled actions
- For manual surgery tools can move freely in space, no wires are needed
- High-precision, e.g. spine or brain surgery, minimally-invasive, with minimal risk
- Improves patient safety
- Precise, controlled actions reduce or eliminate the tissue trauma traditionally associated with open surgery
- Sterilization proof
- Real-time
- Miniature sensor, implant compatible, biocompatible

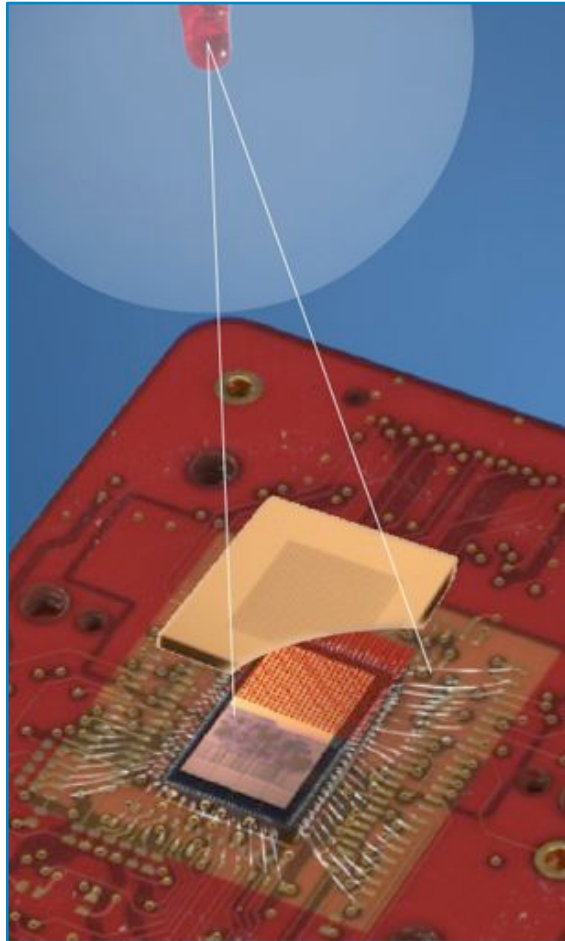


6 DOF pointing device





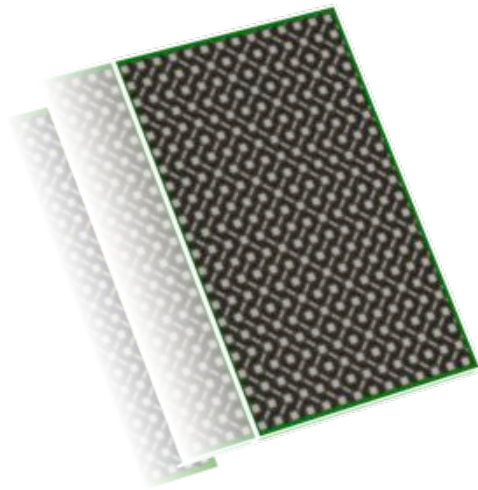
Conclusions ...



... absolute, nanometric measurement systems

- Perfect matching between **vision** and **microelectronic** techniques
- Original approach (patented) using a special pattern
- Extremely **high precision and dynamic** measurement systems
- **Insensitive** to pattern marking and tolerant to contamination
- Small dimensions (size of a **sugar cube**)
- Many configurations possible (1 DOF, 2 DOF, 3 DOF, 6 DOF, linear, rotary)
- **Low cost and compact**

Thank you for your attention.



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+41 32 7205.080

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